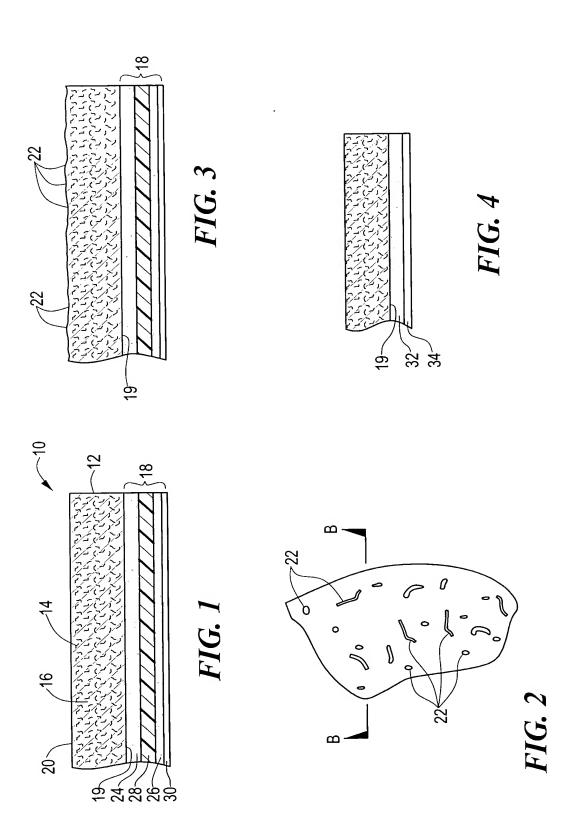
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Title: POLISHING PADS USEFUL IN CHEMICAL MECHANICAL POLISHING OF SUBSTRATES IN THE PRESENCE OF A SLURRY CONTIANING ABRASIVE PARTICLES Inventor Name: Oscar K. Hsu et al. Appl. No. Unassigned Docket No. FREUN-118AX

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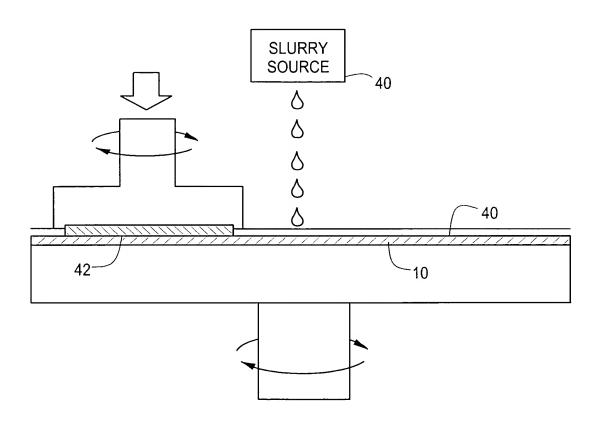


FIG. 5